

Investigation of polarization sensitivity in Superconducting Microstrip Single-Photon Detectors at 1.55 μm

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Superconducting Nanostrip Single-Photon Detectors (SNSPDs) are the current gold standard for photon-starved applications at the 1.55 μm telecommunication wavelength, offering unmatched performance in terms of system detection efficiency (SDE), dark count rates, and time resolutions [1,2]. In order to enhance the active area, SNSPDs are typically arranged in a meandered structure, leaving room for possible polarization sensitivity of the SDE. Depending on the application requirements, these devices can indeed be engineered for either high polarization selectivity [3,4], usually based on anisotropic meanders, or polarization-independent performance [5-7], where fractal or spiral meanders are deployed. Recent studies have also demonstrated that transitioning to Superconducting Microstrip Single-Photon Detectors (SMSPDs) featuring micrometric-scale strips and nanometric gaps (edge-to-edge distance between adjacent strips) ensures polarization-insensitive SDE [8,9]. However, the fabrication of these devices still relies on electron beam lithography, which remains an expensive and time-consuming approach for scaling up to large-area detectors.

In this work, we present the development of MoSi and NbRe-based SMSPDs, successfully patterned in anisotropic meandered structures via UV-lithography. All characterizations were performed at an operating temperature of 2.2 K and at the standard telecommunication wavelength of 1.55 μm , where the devices work as single-photon detectors. Experimental data highlight inherent polarization sensitivity, as shown in Fig. 1 for a NbRe-based meander. This device was fabricated from a 6 nm thick film featuring a 1.6 μm width and a 5.9 μm gap. These results indicate that large-active-area SMSPDs with micrometric gaps can be successfully manufactured to be polarization-sensitive by utilizing UV-lithography.

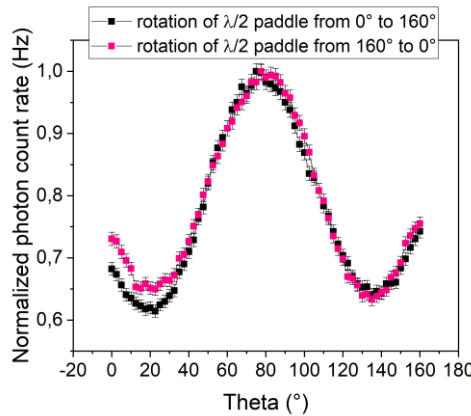


Fig. 1: Polarization sensitivity trend of the normalized photon count rate at 1.55 μm for a 6 nm thick NbRe meander. Dimensions measured via Scanning Electron Microscopy (SEM) indicate a 1.6 μm width and 5.9 μm gap.

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References

- [1] L. You, Nanophotonics 9, 2673 (2020).
- [2] F. P. Venza et al., APL Photonics 10, 040901 (2025).
- [3] Q. Guo et al., Sci Rep 5, 9616 (2015).
- [4] R. Xu et al., Opt. Express 26, 3947-3955 (2018).
- [5] J. Huang et al., Supercond. Sci. Technol. 30, 074004 (2017).
- [6] N. Hu et al., Optica 9, 346-351 (2022).
- [7] Y. Xiao et al., ACS Photonics 9 (10), 3450-3456 (2022).
- [8] G.-Z. Xu et al., Photon. Res. 9, 958-967 (2021).
- [9] D. V. Reddy, APL Photonics 7, 051302 (2022).